

Attorney's Docket No. 5649-842

GRAN 17628
817
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Kang et al. *09/655,208*

Serial No. *09/655,208*

Filed: September 18, 2000

For: *Apparatus for Forming Thin Films and Methods for Forming Capacitors on Semiconductor Substrates Using the Same*

Date: October 5, 2001

Commissioner for Patents
Washington, DC 20231

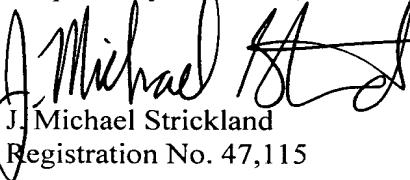
INFORMATION DISCLOSURE STATEMENT

Sir:

Attached is a list of documents on form PTO-1449 together with copies of each identified document. Also enclosed is a translation or a concise explanation of each non-English language document.

This Information Disclosure Statement is submitted in accordance with 37 C.F.R. § 1.97(c), before final Office Action or Allowance, whichever is earlier. In accordance with the requirements of 37 C.F.R. § 1.97(c)(2) this Information Disclosure Statement is accompanied by a check in the amount of \$180.00 as specified in 37 C.F.R. § 1.17(p). The Commissioner is authorized to charge any additional fee, or credit any refund, to our Deposit Account No. 50-0220.

Respectfully submitted,


J. Michael Strickland
Registration No. 47,115

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